

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Timothy A. Gessert)
)
) Group Art: 1741
Serial No.: 08/937,721)
) Examiner: S. Mulpuri
Filing Date: September 25, 1997)
)
Title: ION-BEAM TREATMENT TO) Atty's Dkt. No.: NREL 96-48
PREPARE SURFACES OF)
P-CdTe FILMS)



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TC 2800 MAIL ROOM

AMENDMENT UNDER 37 CFR §1.116

Honorable Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In reply to the Official Action of March 15, 1999, rejecting the claims in the above-identified patent application, applicant respectfully request reconsideration, based upon the amendments hereinafter set forth.

A three month extension is requested, and Applicant authorizes the U.S. Patent and Trademark Office to charge the extension fee in the amount of \$870.00 to Applicant's Deposit

Account 14-0460.

03/06/2000 EMBRY 00000002 140460 08937721

01 FC:217 435.00 CH

IN THE CLAIMS

Adjustment date: 03/06/2000 EMBRY
08/25/1999 RMAGAT 00000002 140460 08937721
01 FC:117 870.00 CH
(Twice Amended) A dry process for making a low-resistance electrical contact between a metal and a layer of polycrystalline p-type CdTe surface by ion beam processing comprising:

a) placing a CdS/CdTe device having a polycrystalline p-type CdTe into a chamber and evacuating said chamber to create a vacuum;

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01 FC:117 870.00 CH